

RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
GROUP 1765
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q82315

Michel PUECH, et al.

Appln. No.: 10/500,654

Group Art Unit: 1765

Confirmation No.: 2879

Examiner: Mahmoud DAHIMENE

Filed: July 2, 2004

For: A METHOD AND APPARATUS FOR ANISOTROPICALLY ETCHING SILICON
WITH A HIGH ASPECT RATIO

RESPONSE UNDER 37 C.F.R. § 1.116

MAIL STOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated June 15, 2006, please consider the remarks as
submitted herewith on the accompanying pages.

REMARKS

Claims 1-16 have been examined and have been rejected under 35 U.S.C. § 103(a).

I. Preliminary Matter

As a preliminary matter, Applicant respectfully requests withdrawal of the finality of the
Office Action. The only feature added in the March 28, 2006 Amendment, which the Examiner